

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination	
		10/807,944	DE REGE THESAURO ET AL.	
Examiner		Art Unit	Patricia A. George	
		1765	Page 1 of 1	

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Appendix Main Wear Mechanisms in CMP; A Model for Mechanical Wear and Abrasive Particle Adhesion during the CMP Process by Ahmadi et al.; Department of Mechanical and Aeronautical Engineering, Clarkson University, Potsdam, New York; Submitted: April 18, 2000; revised: August 31, 2000
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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